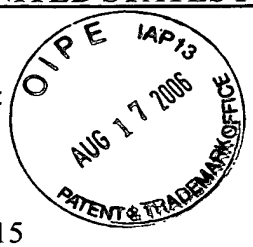
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re the Application of:

Im-soo PARK, et al.

Art Unit: 1746

Serial No.: 10/685,515

Examiner: Saeed T. Chaudhry

Filed: October 16, 2003

Confirmation No.: 8169

For: APPARATUS FOR CLEANING SEMICONDUCTOR WAFER INCLUDING HEATING USING A LIGHT SOURCE AND METHOD FOR CLEANING WAFER USING THE SAME (AS AMENDED)

Attorney Docket No.: 249/255 DIV

REPLY UNDER 37 C.F.R. § 1.111

Mail Stop: Amendments
Commissioner for Patents
United States Patent and Trademark Office
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office action dated May 17, 2006, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

A Listing of the Claims are reflected in a listing of claims, which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.